

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Shiva Prakash
Title: Atomic Force Microscopy Measurements Of Contact Resistance And Current-Dependent Stiction
Serial No. New – Divisional of Serial No. 10/202,439 filed 07/23/2002
Filing Date: Herewith
Prior Art Unit: 2856
Prior Examiner: R. Raevis
Atty Docket: 061450/0304608 (FID-101-D4)

MAIL STOP: Patent Applications
Commissioner for Patents
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Kathleen M. Smith

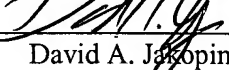
INFORMATION DISCLOSURE STATEMENT

Applicant submits herewith patents, publications or other information of which Applicant is aware which are believed to be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR 1.56.

The filing of this information disclosure statement shall not be construed as a representation that a search has been made (37 CFR 1.97(g)), nor as an admission that the information cited is, or is considered to be, material to patentability, nor an admission that no other material information exists. The filing of this information disclosure statement shall not be construed as an admission against interest in any manner. Notice of January 9, 1992, 1135 O.G. 13-25, at 25.

The references cited herein were cited in the parent application Serial No. 10/202,439 filed July 23, 2002, and therefore copies are not included.

Respectfully submitted
PILLSBURY WINTHROP LLP

By 
David A. Jakopin Reg. No. 32,995

1600 Tysons Boulevard
McLean, VA 22102
Telephone No. 650-233-4500

INFORMATION DISCLOSURE CITATION PTO-1449		Atty Docket: 061450/0304608 FID-101-D4		Serial No. to be assigned			
Submitted: July 3, 2003		Applicant: S. Prakash					
		Filing Date: Herewith		Prior Group Art Unit: 2856			
U.S. PATENT APPLICATIONS							
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE	
	5,723,981	03 Mar 1998	Hellemans et al.	324	719	06/25/96	
	5,992,226	11/1999	Green et al.	73	105		
	5,763,768	06/1998	Henderson, et al.	73	105		
FOREIGN PATENT DOCUMENTS							
EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						Yes	No
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)							
	De Wolf, et al. "Lateral and vertical dopant profiling in semiconductors by atomic force microscopy using conducting tops" (J. Vac. Sci. Tech. A 13(3), May/June 1995, pp. 1699-1704)						
EXAMINER			DATE CONSIDERED				

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.